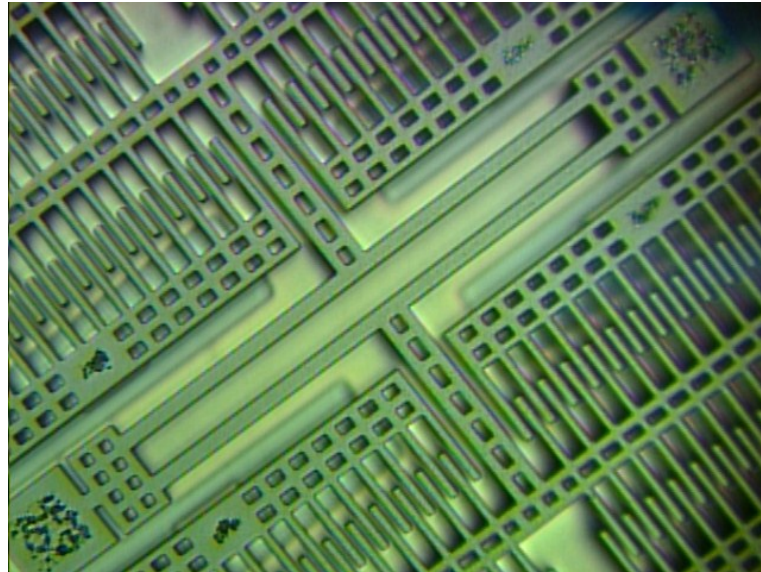


# Resonant Strain Sensor

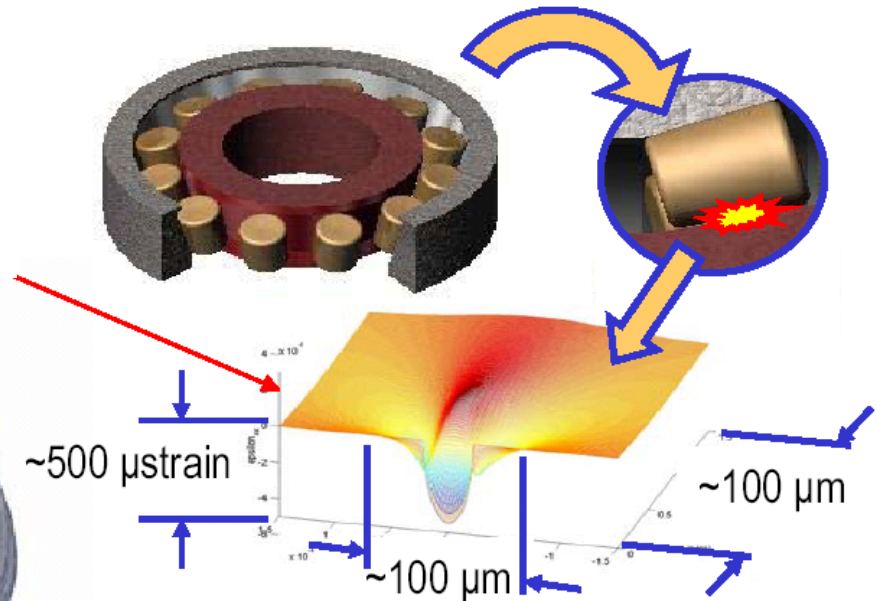
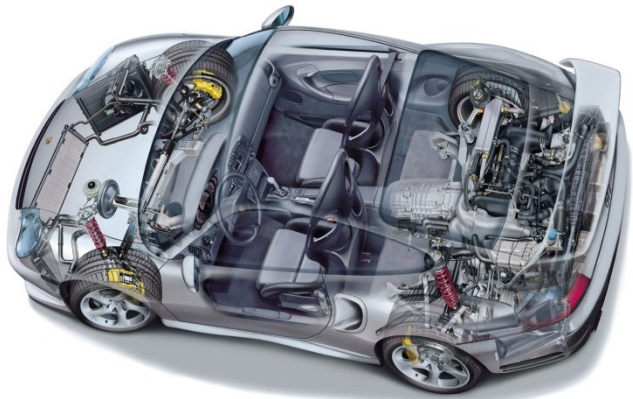


K. E. Wojciechowski and Bernhard E. Boser  
Berkeley Sensor & Actuator Center  
Dept. of Electrical Engineering and Computer Sciences  
University of California, Berkeley

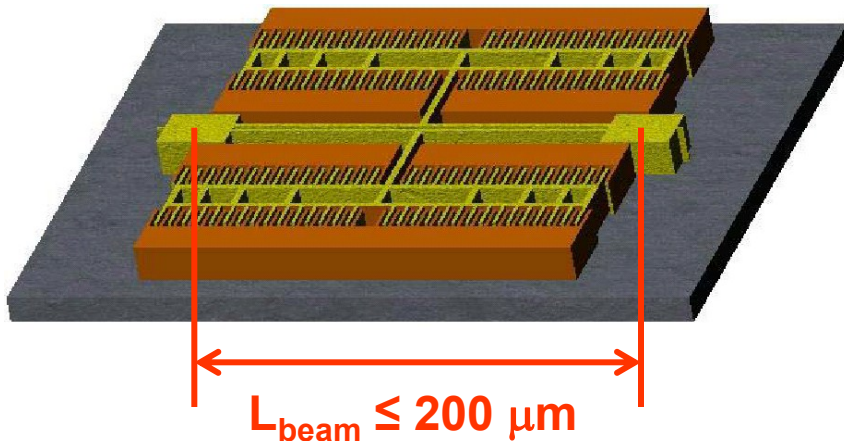
# Outline

- Strain sensor
- Resonant force sensing
- Oscillator analysis
  - Phase and frequency noise
  - Design for minimum noise
- Oscillator sustaining circuit
- Frequency-to-digital conversion
- Conclusions

# Strain Sensor Applications



# Strain Sensor Specifications

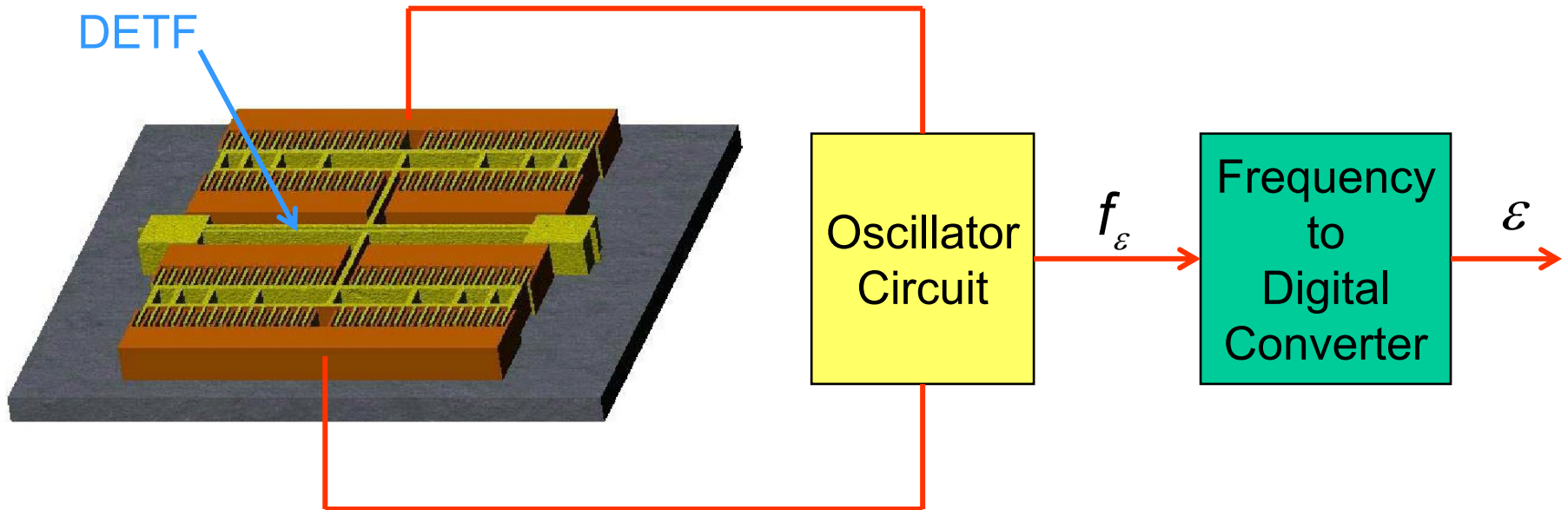


- Resolution:  $0.1 \mu\epsilon$
- Full-scale:  $\pm 1000 \mu\epsilon$
- Bandwidth:  $10 \text{ kHz}$
- Gauge length:  $\leq 200 \mu\text{m}$

Strain:  $\epsilon = \frac{\Delta L_g}{L_g}$

$$\begin{aligned}\Delta L_g &= \epsilon \times L_g \\ &= 0.1 \mu \times 200 \mu\text{m} \\ &= 20 \text{ pm} \\ &= \underline{\underline{0.2 \times 10^{-10} \text{ m}}}\end{aligned}$$

# Resonant Strain Sensor



Frequency Modulation:

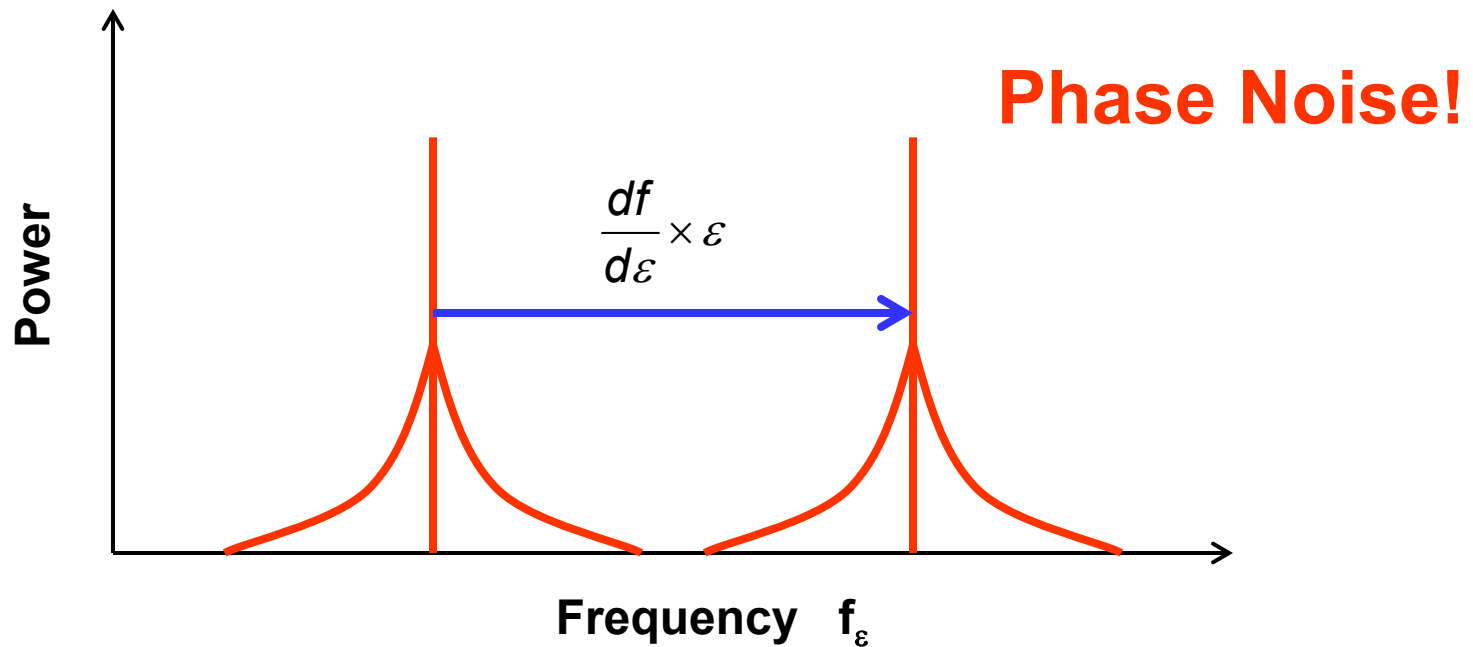
$$f_\epsilon = f_o + \frac{df}{d\epsilon} \times \epsilon$$

This design:

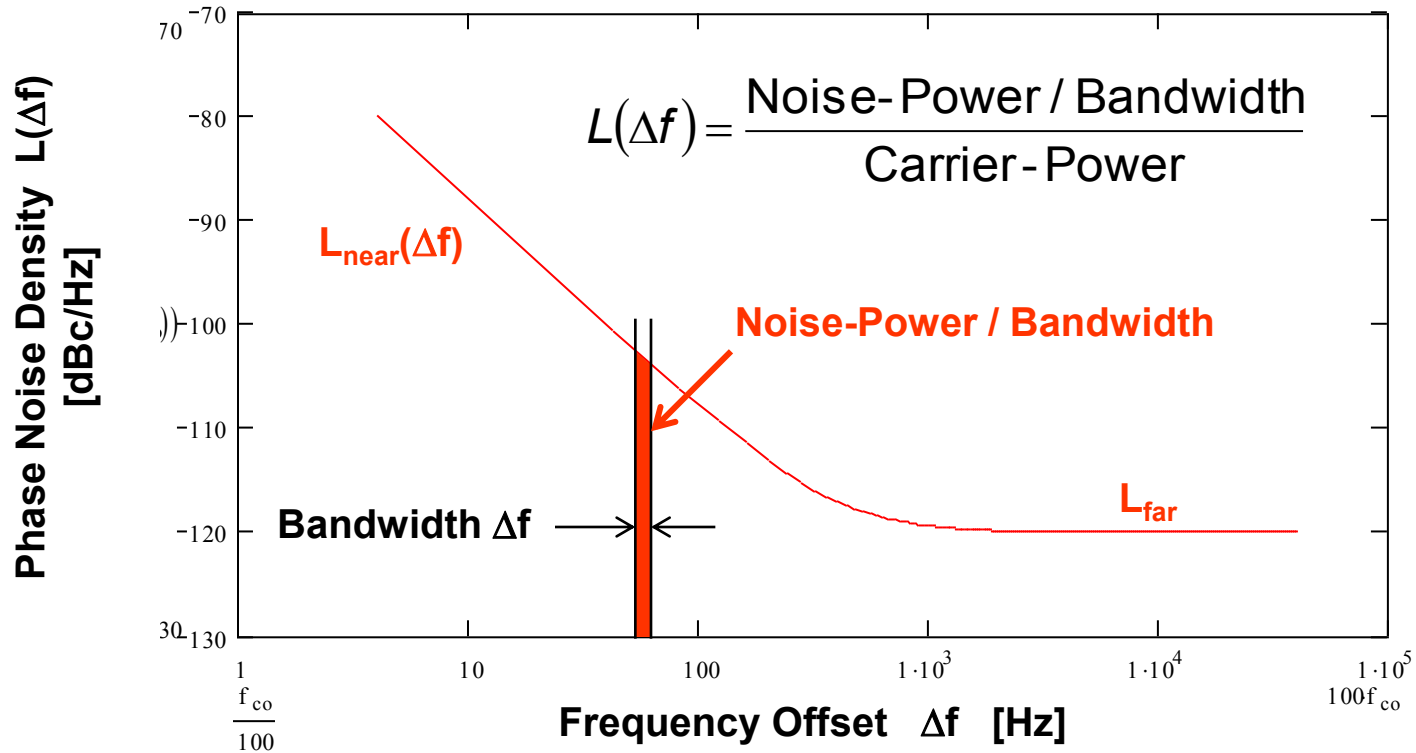
$$f_o = 217\text{kHz}$$

$$\frac{df}{d\epsilon} = 38\text{Hz}/\mu\epsilon$$

# Frequency Modulation



# Phase Noise



# Frequency Noise

Frequency Noise  $S_f(\Delta f) = 2 \times (\Delta f)^2 \times L(\Delta f)$

Total Noise  $S_{fT} = 2 \int^B S_f(\Delta f) d\Delta f$

$$\cong 2 \int^B (\Delta f)^2 L_{far} d\Delta f \quad \text{for } B \gg f_{co}$$

$$= \frac{2}{3} B^3 L_{far}$$

Phase Noise  $L_{far} \leq 1.5 \times \frac{S_{fT}}{B^3}$

$$= 1.5 \times \frac{(3.8\text{Hz})^2}{2 \times (10\text{kHz})^2} = \underline{\underline{-110\text{dBc/Hz}}}$$



# Prior Art MEMS Resonators

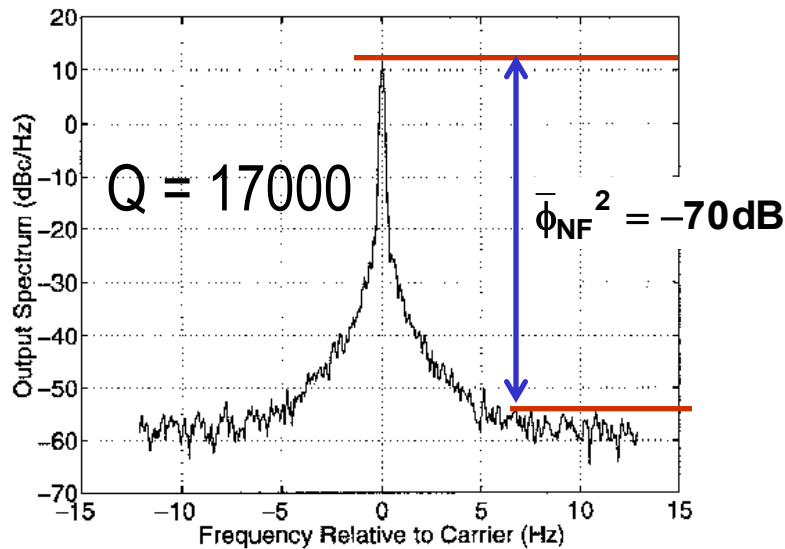
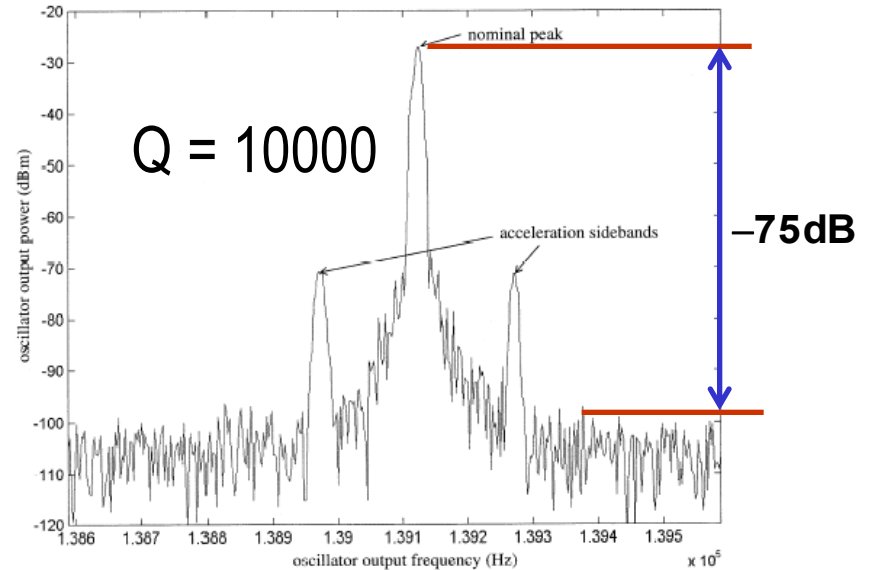


Figure 5. Output spectrum of oscillator

[T. Roessig , 1997]



[A. Seshia , 2002]

- Vacuum encapsulation
- Integrated electronics
- Much worse than quartz – why?

# MEMS Oscillator Noise

	Roessig 1997	Nguyen 1999	Seshia 2002	Seth 2004	Goal (This Work)
Noise $L_{\text{far}}$ [dBc/Hz]	<b>-70</b>	<b>-70</b>	<b>-75</b>	<b>-83</b>	<b>&lt; -110</b>
Vacuum	✓	✓	✓	✓	x
Monolithic	✓	✓	✓	x	x
Frequency, $f_o$	175 kHz	16.5 kHz	145 kHz	57 kHz	217 kHz
Motional Res., $R_x$	?	3.8 M $\Omega$	?	2.5 M $\Omega$	
Q	17000	51000	10000	14000	
Amplitude $V_{\text{Drive}}$	?	~ 34 mV	~36 mV	5.3 mV	

**Need oscillator with 1000x lower noise than prior art!**



# Low-Noise Oscillator Design

$$L(\Delta f) = \frac{\text{Noise-Power / Bandwidth}}{\text{Carrier-Power}}$$

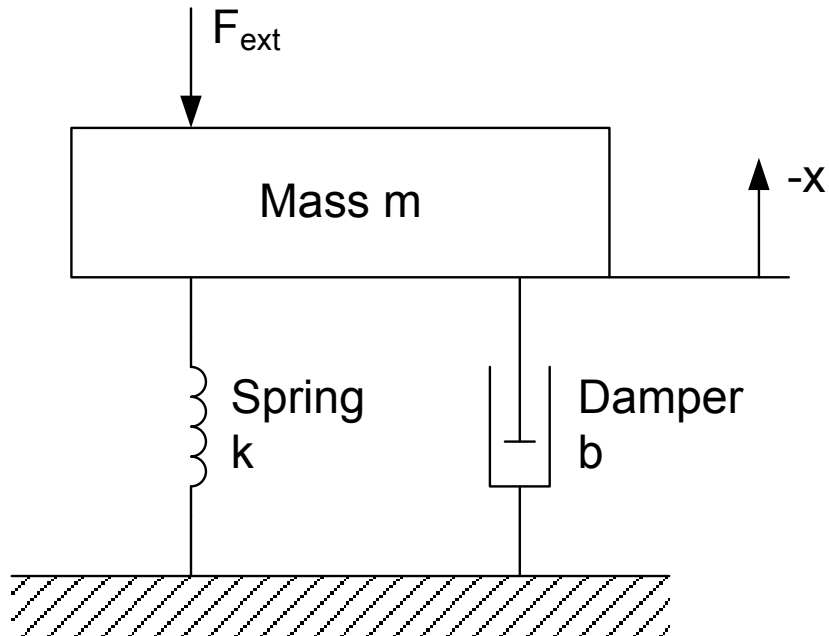
← small

← **BIG!**

Constrained by gap,  
nonlinearity

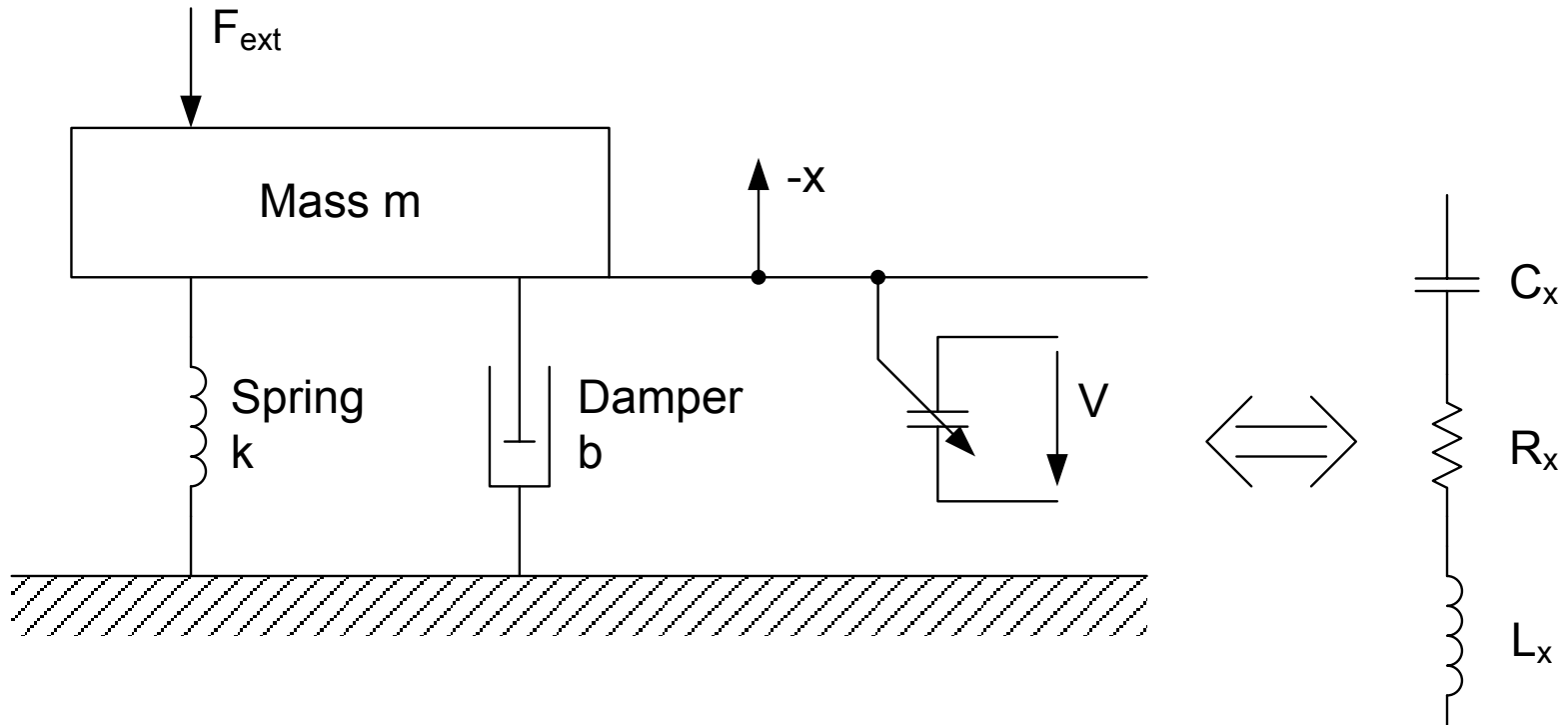
What is the noise power?

# Electro-Mechanical Oscillator



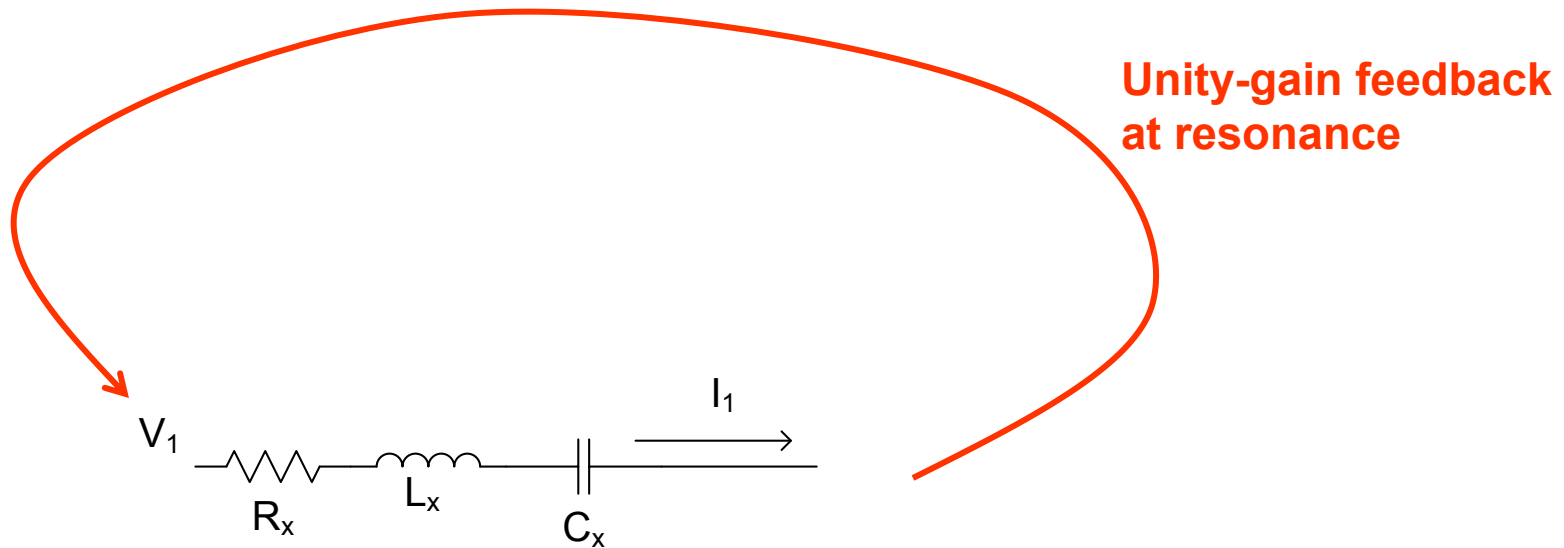
$$F_{ext} = kx + b\dot{x} + m\ddot{x}$$

# Electro-Mechanical Oscillator

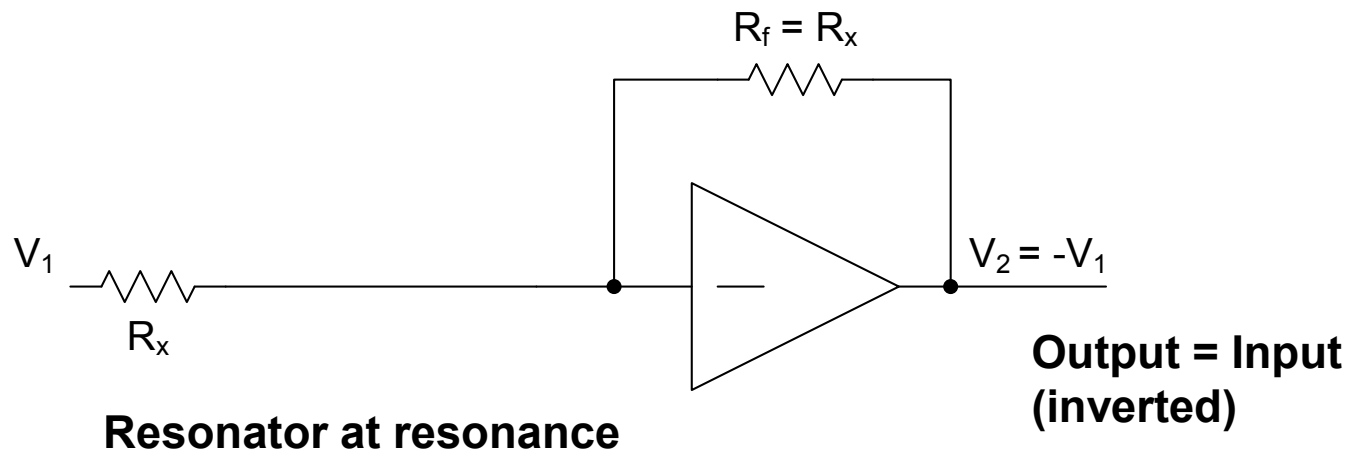


$$F_{ext} = kx + b\dot{x} + m\ddot{x}$$

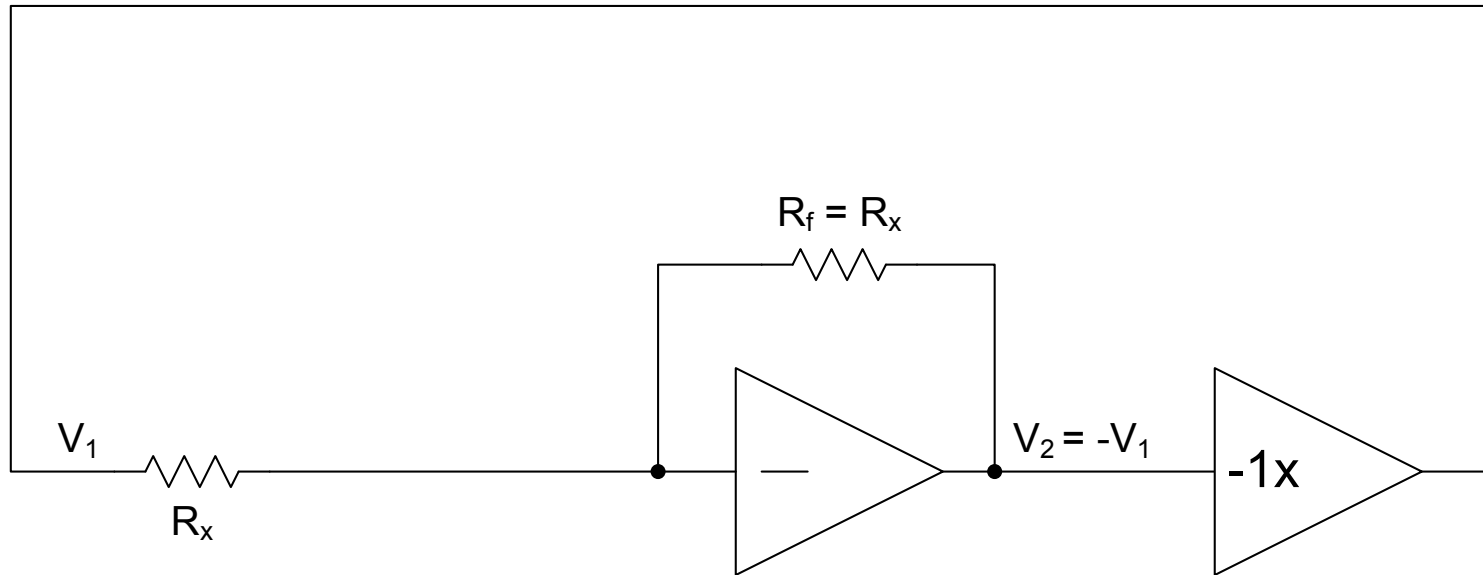
# Oscillator Sustaining Circuit



# Oscillator Sustaining Circuit

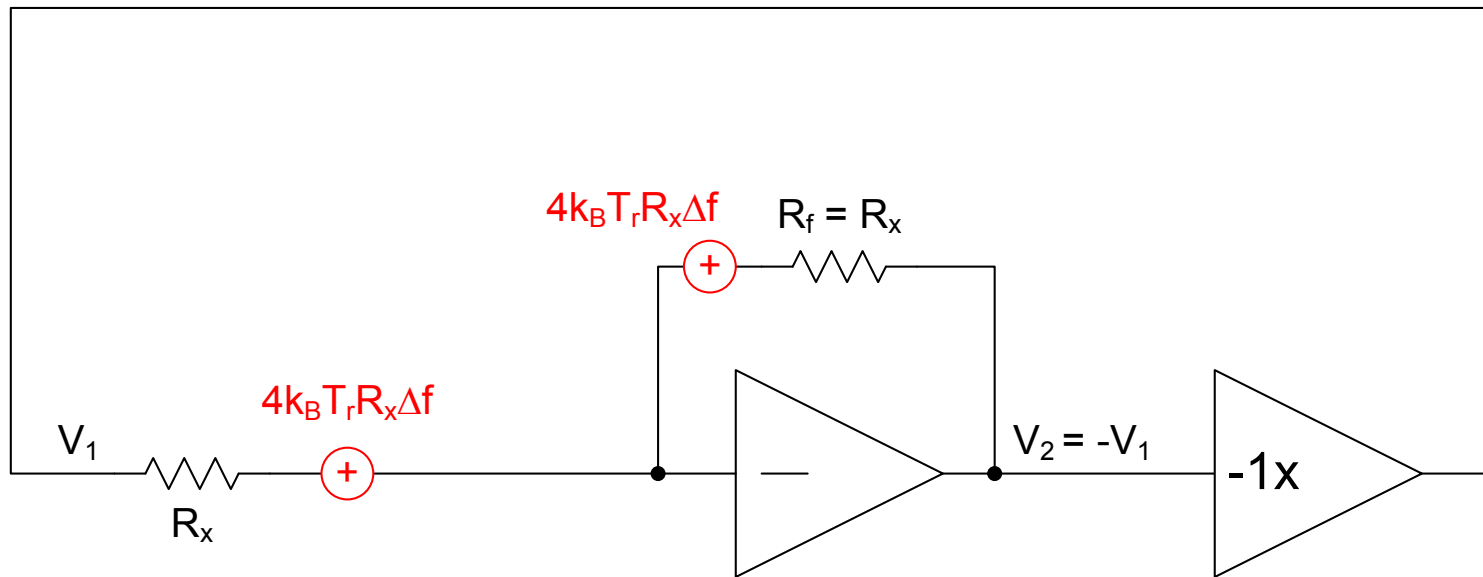


# Oscillator Sustaining Circuit





# Oscillator Noise Voltage



$$\overline{v_{n1}^2} = 4k_B T_R R_x \left[ 1 + 2 \left( \frac{f_o}{2Q\Delta f} \right)^2 \right] df \quad \leftarrow \text{High Q?}$$

# Phase Noise

$$L(\Delta f) = \frac{\text{noise-power}}{\text{power delivered to oscillator}}$$

$$= \frac{\frac{\overline{v_{n1}^2}}{R_x}}{\frac{\underbrace{k_B X^2}_{\text{energy stored in spring}} \omega_o}{Q}}$$

$$= \frac{2k_B T_r}{k_B X^2 \omega_o} Q \left[ 1 + 2 \left( \frac{f_o}{2Q\Delta f} \right)^2 \right]$$

$$= \frac{2k_B T_r}{k_B X^2 \omega_o} \left[ \underbrace{Q}_{L_{far}} + \underbrace{\frac{2}{Q} \left( \frac{f_o}{2\Delta f} \right)^2}_{L_{near}} \right]$$

$$L_{near} = \frac{4k_B T_r}{k_B X^2 \omega_o} \frac{1}{Q} \left( \frac{f_o}{2\Delta f} \right)^2$$

$$L_{far} = \frac{2k_B T_r}{k_B X^2 \omega_o} Q$$

- tradeoff  
(for high bandwidth optimal Q < 100)
- for given mechanical amplitude

# Phase Noise Floor – Interpretation

$$L_{far} = \frac{2k_B T_r}{k_B X^2 \omega_o} Q$$

$$= \frac{\text{Thermal Energy}}{\text{Energy Replenished by Electronics}}$$

$$= \frac{\text{Thermal Energy}}{\text{Energy Stored in Resonator} / Q}$$

Set by thermodynamics

Resonator properties (size)

Resonator quality  
Sets long-term stability

# MEMS versus Quartz Resonators

## 1. Maximum power limited in “small” MEMS oscillators

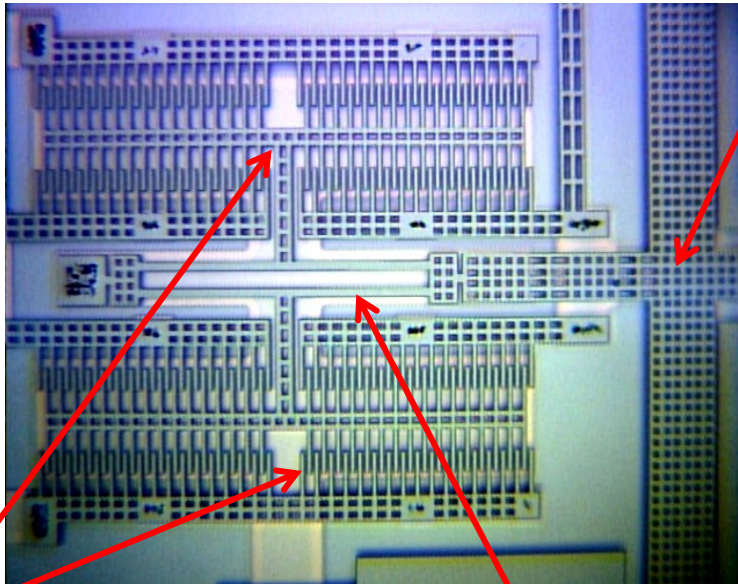
- Increasing resonant frequency helps
- Bulk acoustic waves store more energy

## 2. High motional impedance $R_x$

- Loaded  $Q \approx$  intrinsic  $Q$

# Prototype DETF Strain Sensor

Strain Actuator

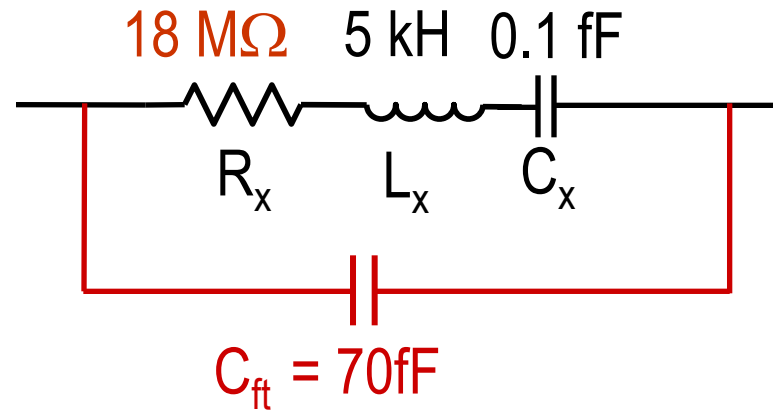


<i>Gauge Length (<math>L_{beam}</math>)</i>	200 $\mu\text{m}$
<i>Width, (<math>W_{beam}</math>)</i>	6 $\mu\text{m}$
<i>Measured Resonant freq. (<math>f_r</math>)</i>	217kHz
<i>Measured Q (atmospheric pressure)</i>	370
<i>Measured sensitivity</i>	38Hz/ $\mu\epsilon$

Comb drive interface capacitors for sustaining circuit

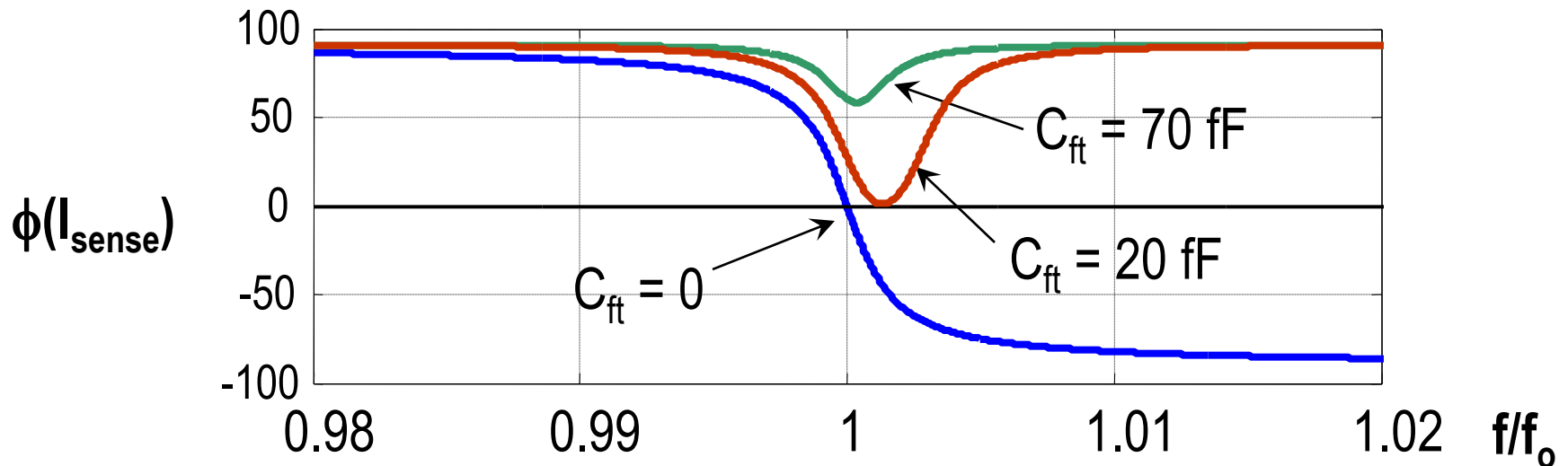
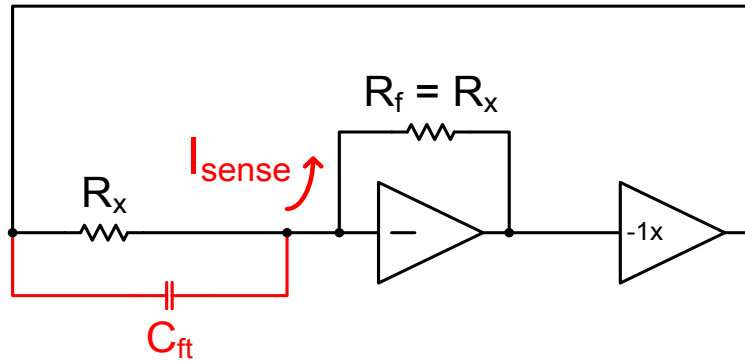
Double-ended tuning fork (DETF).

# Problem with Low Q Operation

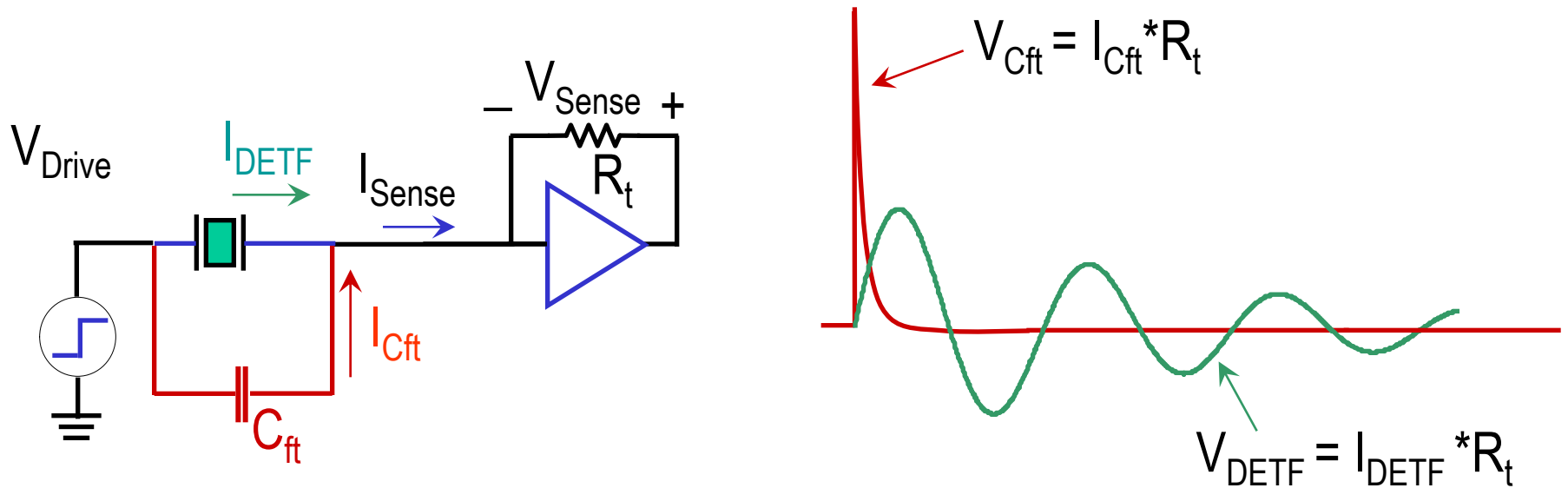


- No vacuum packaging ( $Q \sim 370$ )
  - Large feature spacing  $\sim 3\mu\text{m}$  gaps
  - Modest  $V_{\text{bias}} = 30\text{V}$
  - No integration: PCB parasitics
- Large  $R_x$
- Large  $C_{ft}$

# Effect of $C_{ft}$ on Sustaining Circuit



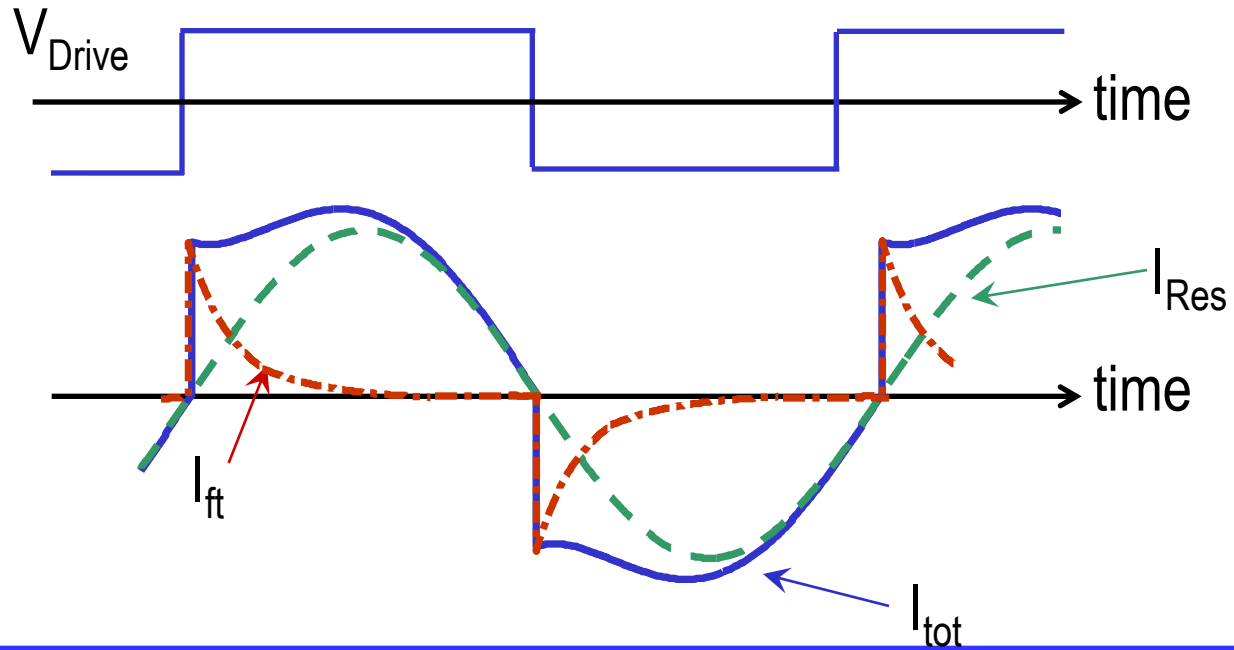
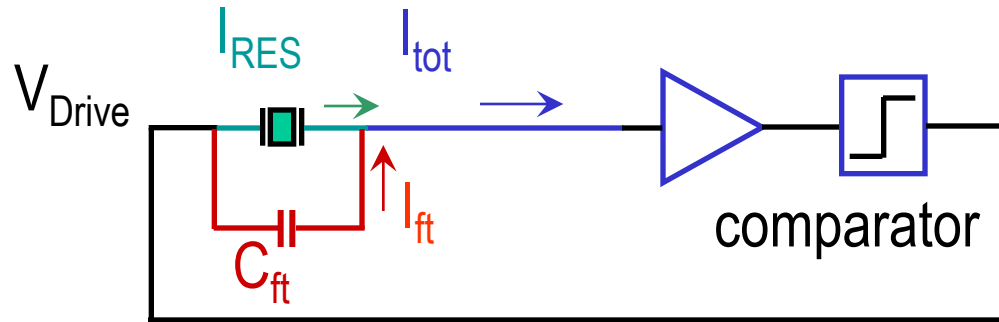
# Time-Variant Sustaining Circuit



- Undesired  $I_{\text{Cft}}$  decays *quickly*
- Sinusoidal  $I_{\text{DETF}}$  decays *slowly*
- Zero crossings set by *DETF*, not  $C_{\text{ft}}$

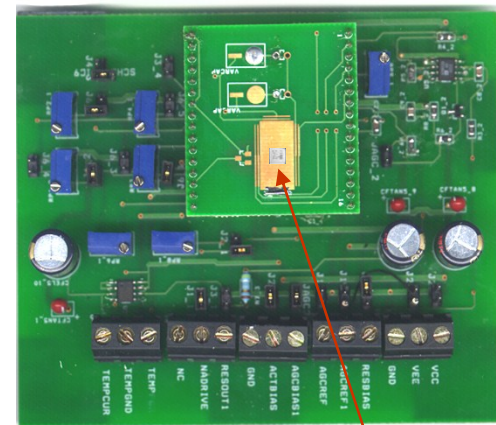
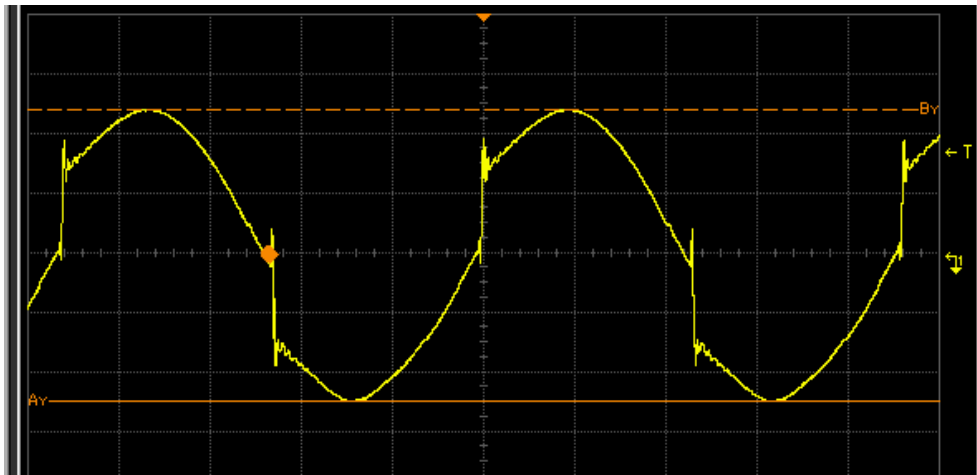


# Time-Variant Oscillator (TVO)



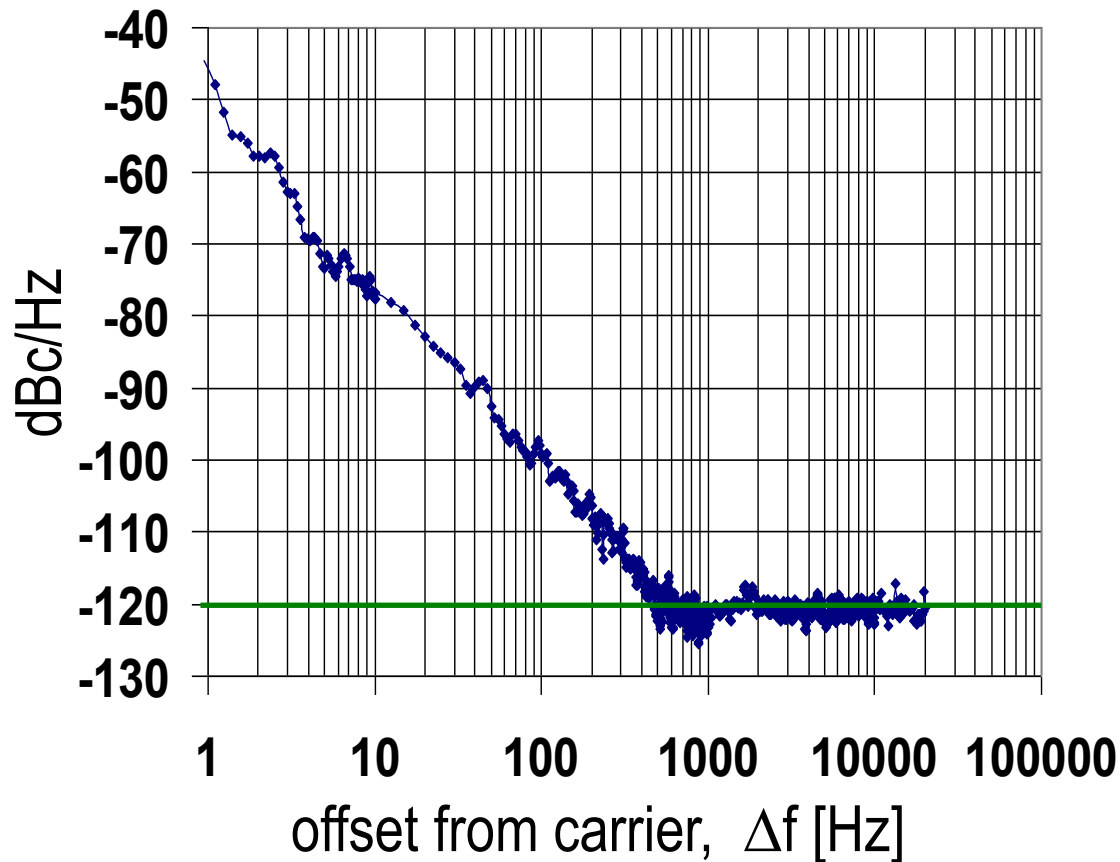
# TVO Measurements

Measured Output:  $V_{\text{Sense}}$



MEMS  
resonator

# Measured TVO Phase Noise



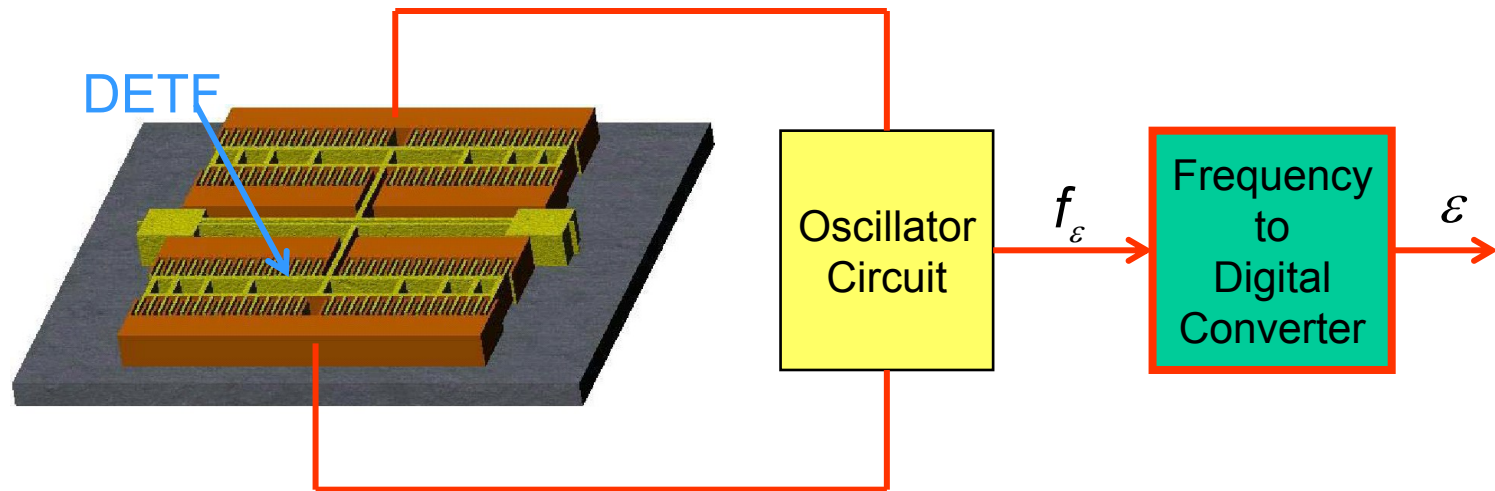
- Resolution
  - 20-nε in 10kHz
  - 200-pε/rt-Hz
  - 40-fm/rt-Hz
- Test equipment:  
Agilent 5501A

# MEMS Oscillator Noise

	Roessig 1997	Nguyen 1999	Seshia 2002	Seth 2004	This Work 2004
Noise $L_{\text{far}}$ [dBc/Hz]	<b>-70</b>	<b>-70</b>	<b>-75</b>	<b>-83</b>	<b>-120</b>
Vacuum	✓	✓	✓	✓	✗
Monolithic	✓	✓	✓	✗	✗
Frequency, $f_o$	175 kHz	16.5 kHz	145 kHz	57 kHz	217 kHz
Motional Res., $R_x$	?	3.8 M $\Omega$	?	2.5 M $\Omega$	18 M $\Omega$
Q	17000	51000	10000	14000	370
Amplitude $V_{\text{Drive}}$	?	~ 34 mV	~36 mV	5.3 mV	10 V



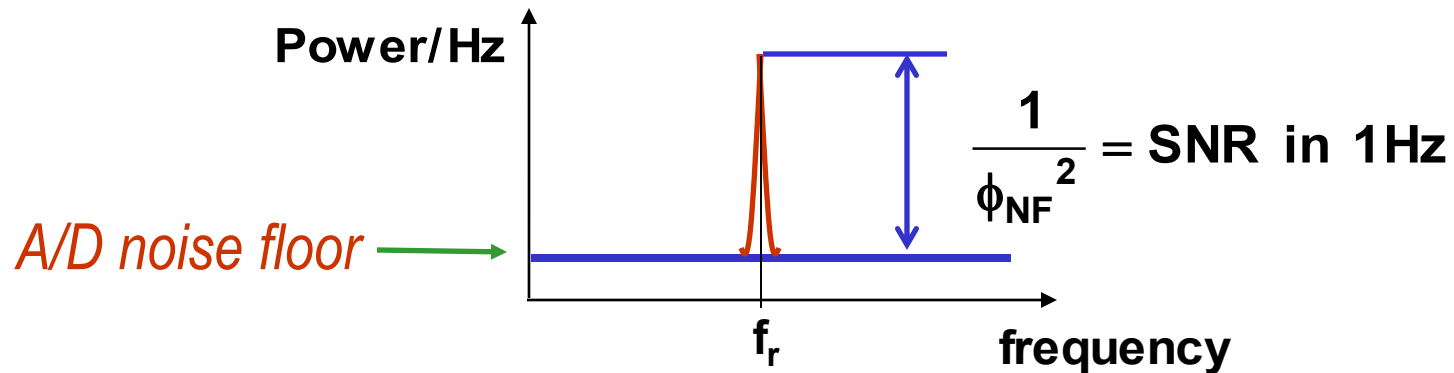
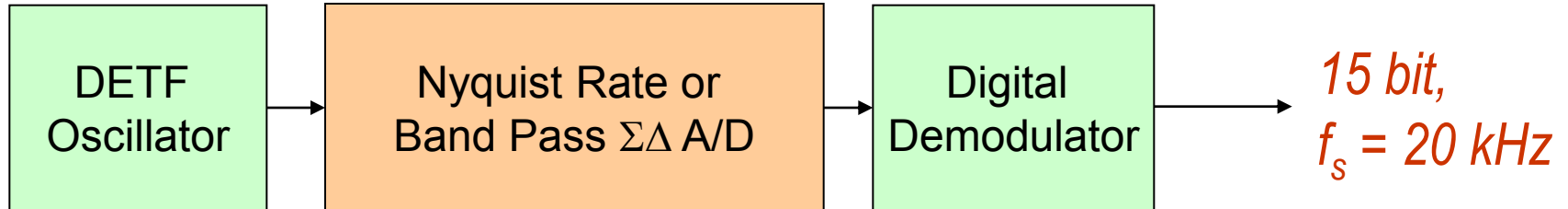
# Frequency-to-Digital Conversion



Methods:

- Digital demodulation
- Analog PLL followed by ADC
- $\Sigma\Delta$ PLL

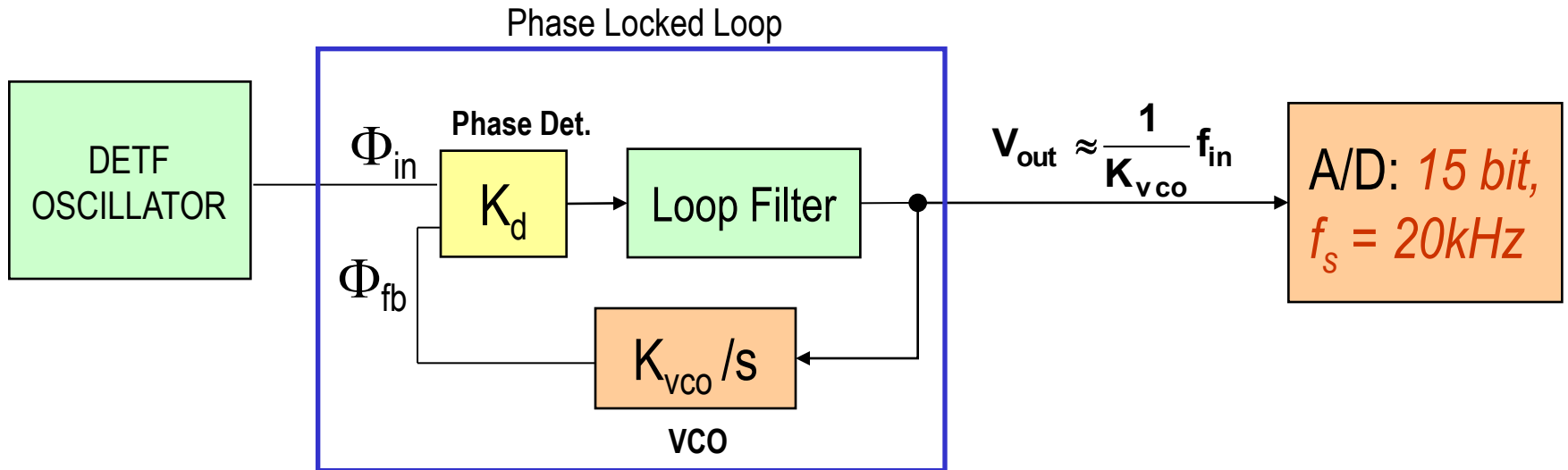
# Digital Demodulation



## ADC Specs:

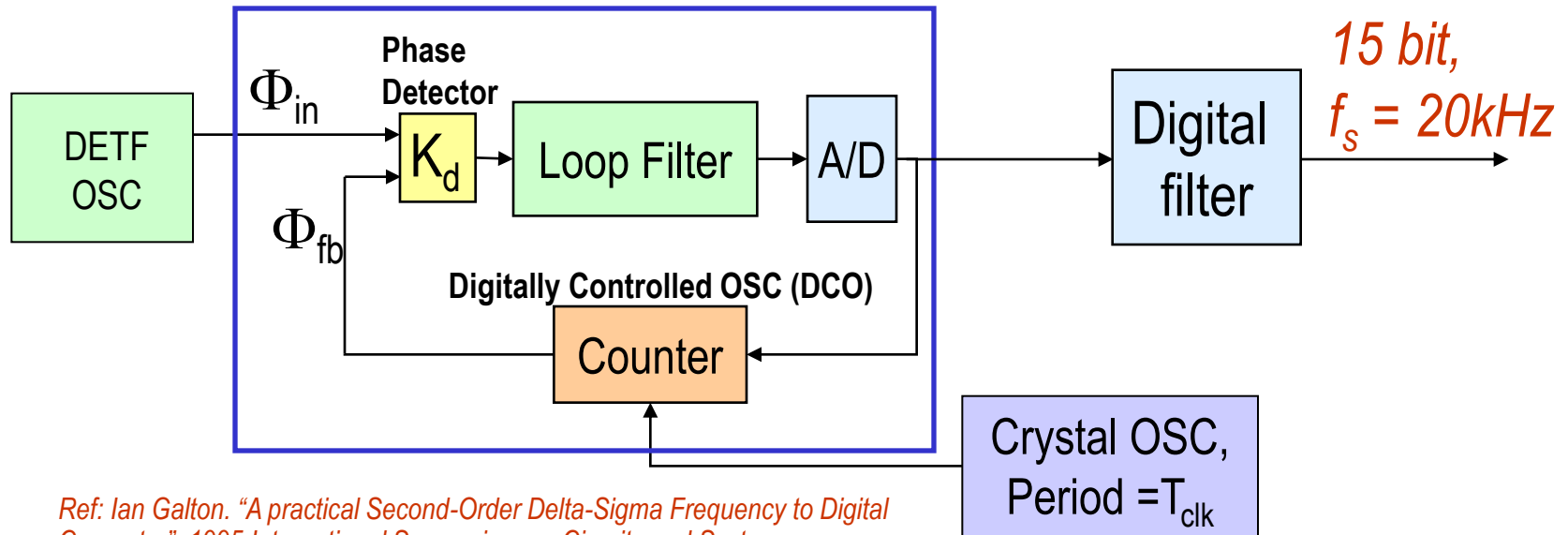
- 17 Bit A/D required
- Sample Rate  $f_s \geq 3f_r = 651 \text{ kHz}$
- Bandwidth  $\geq 2 \times (\text{Signal BW} + \text{Max change in } f_r) = 96 \text{ kHz}$

# PLL Demodulator



- *Loop filter Bandwidth  $\geq$  Signal Bandwidth (10kHz)*
- *VCO phase noise better than input phase noise (-120 dBc).*
- *Scale factor ( $K_{VCO}$ ) temp/supply dependence can be problem*
- *Needs extra ADC*

# Solution: $\Sigma\Delta$ PLL\* Approach



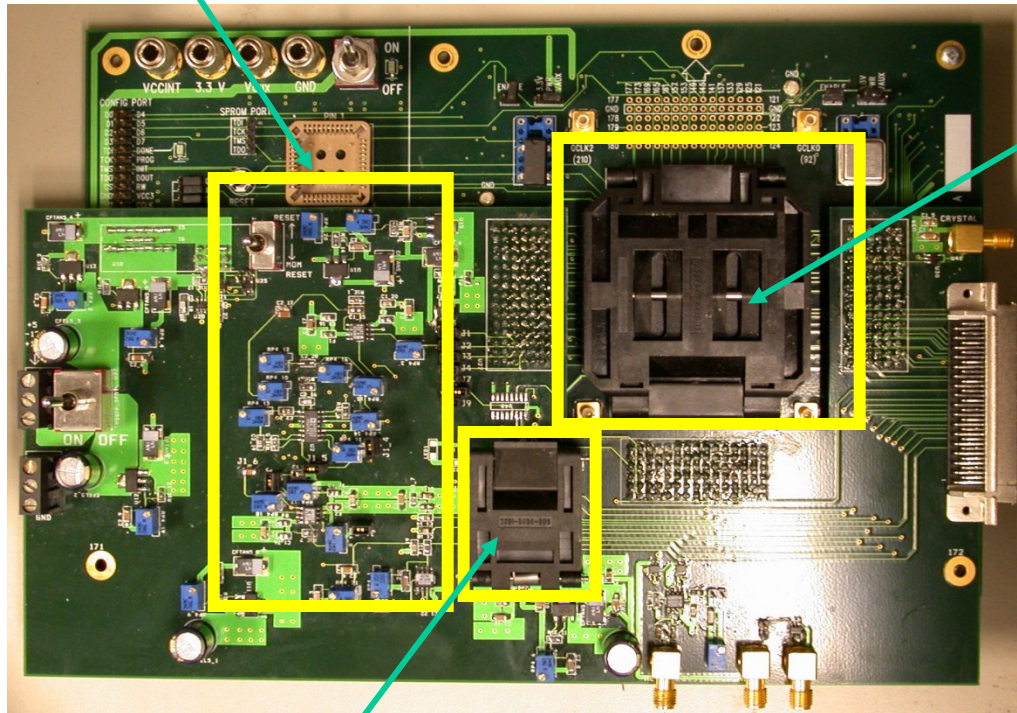
Ref: Ian Galton. "A practical Second-Order Delta-Sigma Frequency to Digital Converter", 1995 International Symposium on Circuits and Systems.

- *Performs demodulation and A/D conversion in same step*
- *Low complexity analog filter and A/D (4 bits) for 15 bit resolution*
- *Linearity and phase noise set by crystal reference*
- *Loop filter Bandwidth = Signal Bandwidth (10kHz)*



# Frequency-to-Digital Converter

Analog Filter



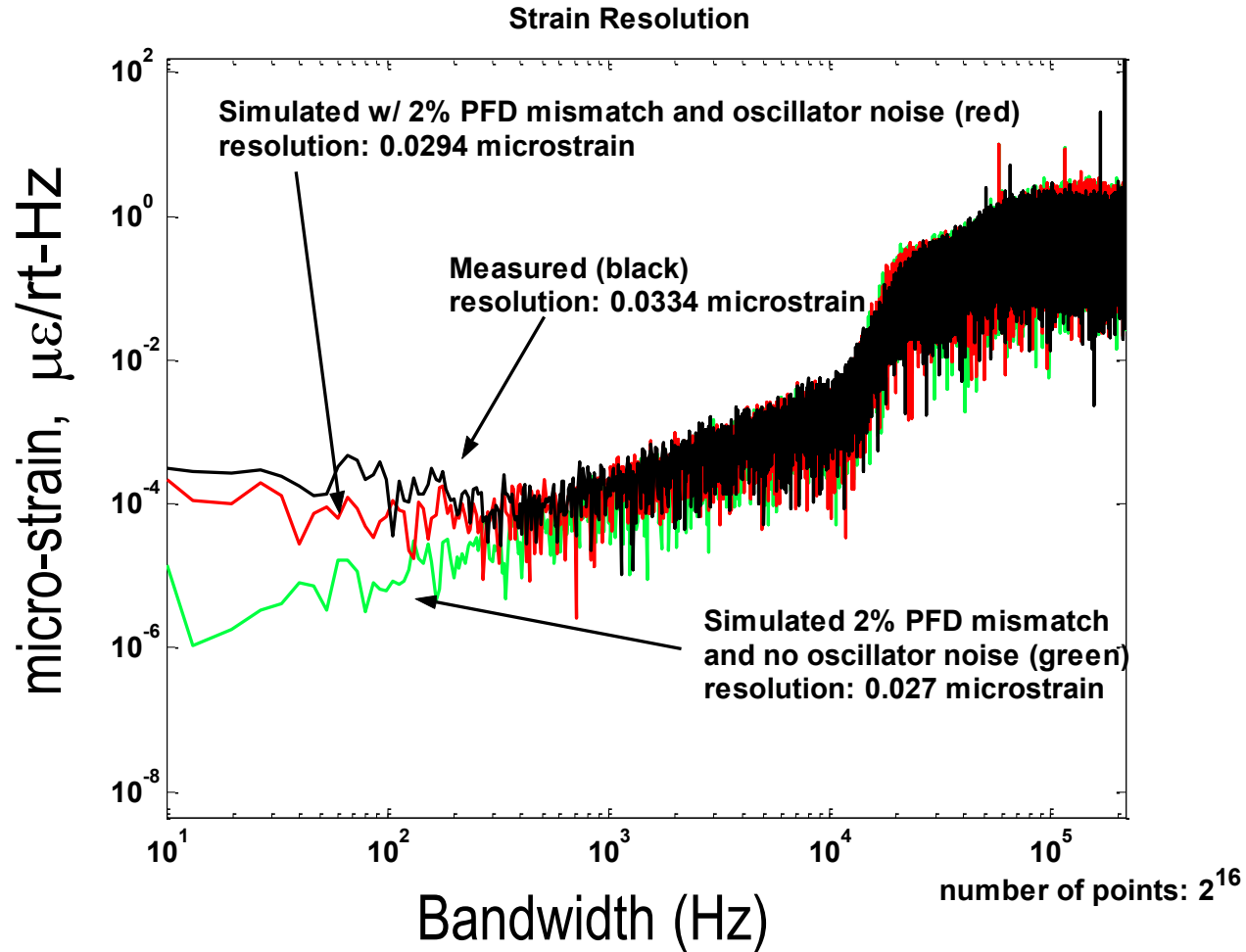
FPGA

Output:  
Digitized frequency  
→ strain

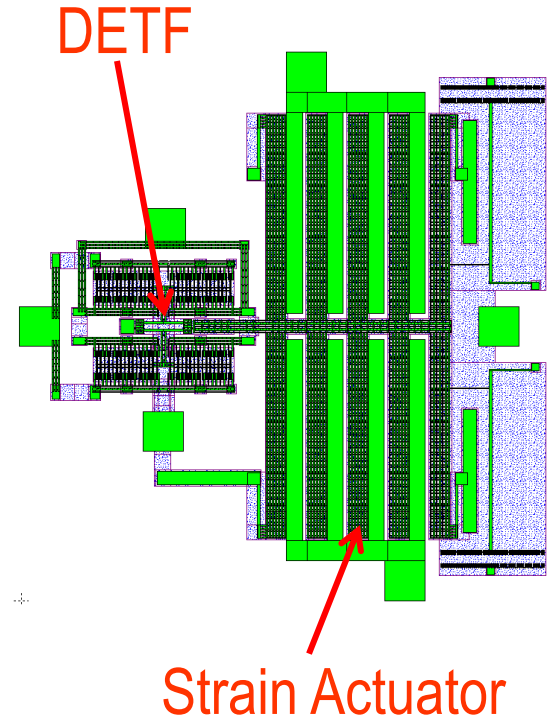
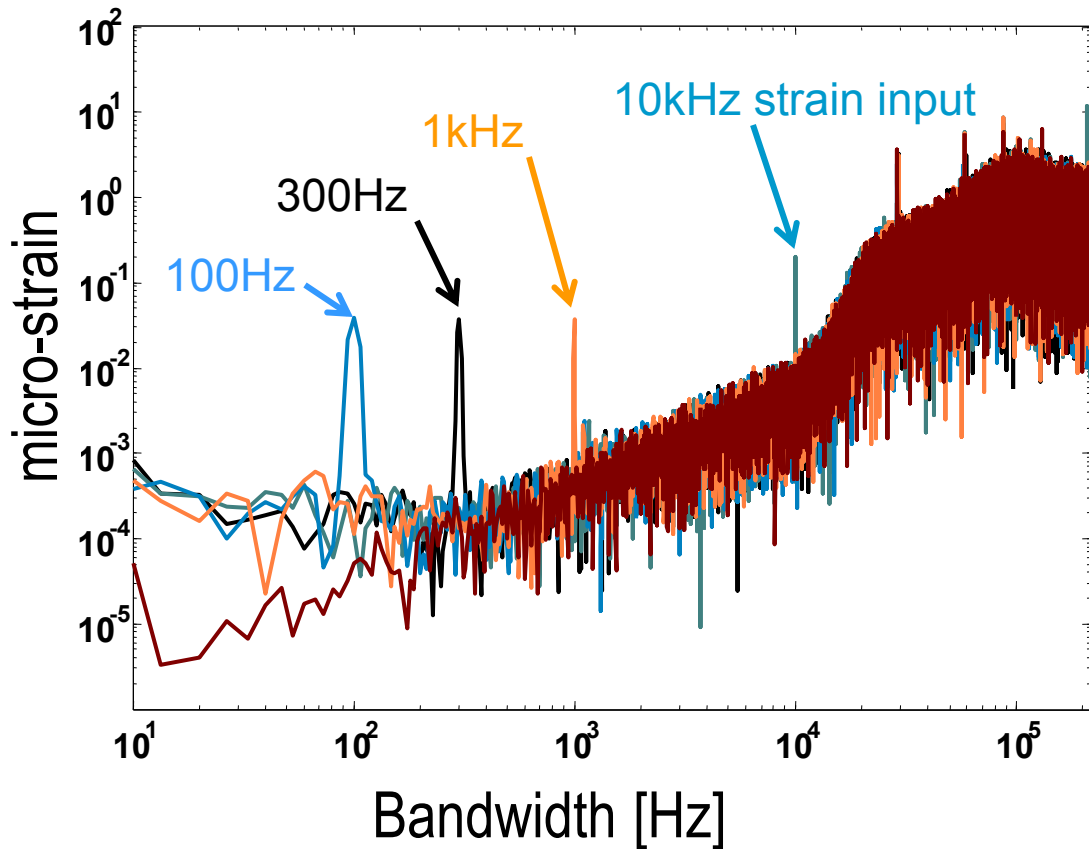
4bit  
A/D Converter

Input from: DETF Strain  
Gauge Oscillator

# Measured Strain Resolution



# Test with Strain Actuator



# Conclusions

- High resonator Q translates into
  - Low signal power delivered to resonator
  - High phase noise
  - Lowest phase noise is achieved for moderate Q
- High motional resistance,  $R_x$ 
  - Typical for MEMS oscillators, exacerbated in low Q designs
  - Incompatible with conventional oscillator circuits
  - Overcome with time-variant sustaining circuit
- Strain sensor performance
  - 20-n $\epsilon$  (rms) resolution in 10kHz
  - 200- $\mu$ m gauge length
  - 40-fm/rt-Hz displacement resolution

# Acknowledgements

- BSAC strain sensor research team under Professor Albert Pisano
- Wayne Denny and Graham Mcdearmon of Timken Company
- Bosch RTC for help with testing
- Bosch for fabrication
- Vladimir Petkov, Baris Cagdaser, Manu Seth
- Army Research Office grant # 19-02-1-0198

